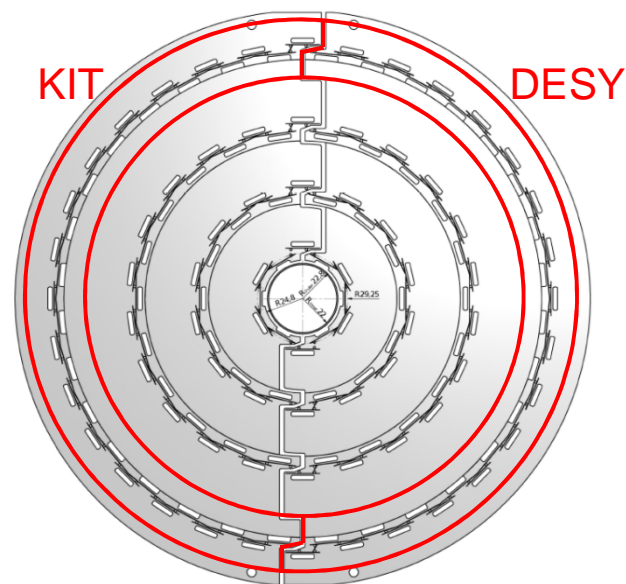


CMS DPIX Bump Bonding Activities.

Facility Test Results and Plans

DPIX volume

- 512 modules (~42% BPIX)
- ~ 12k ROC to be bonded
- ~53M bump bonds



Jan Hampe, Karsten Hansen (DESY)

Michele Caselle, Thomas Blank (KIT)

Phase I Pixel Upgrade Workshop

Grindelwald, August 28th, 2012

Outline

- > Evaluation of Bumping Methods
- > Flip-Chip Bonder Test Results

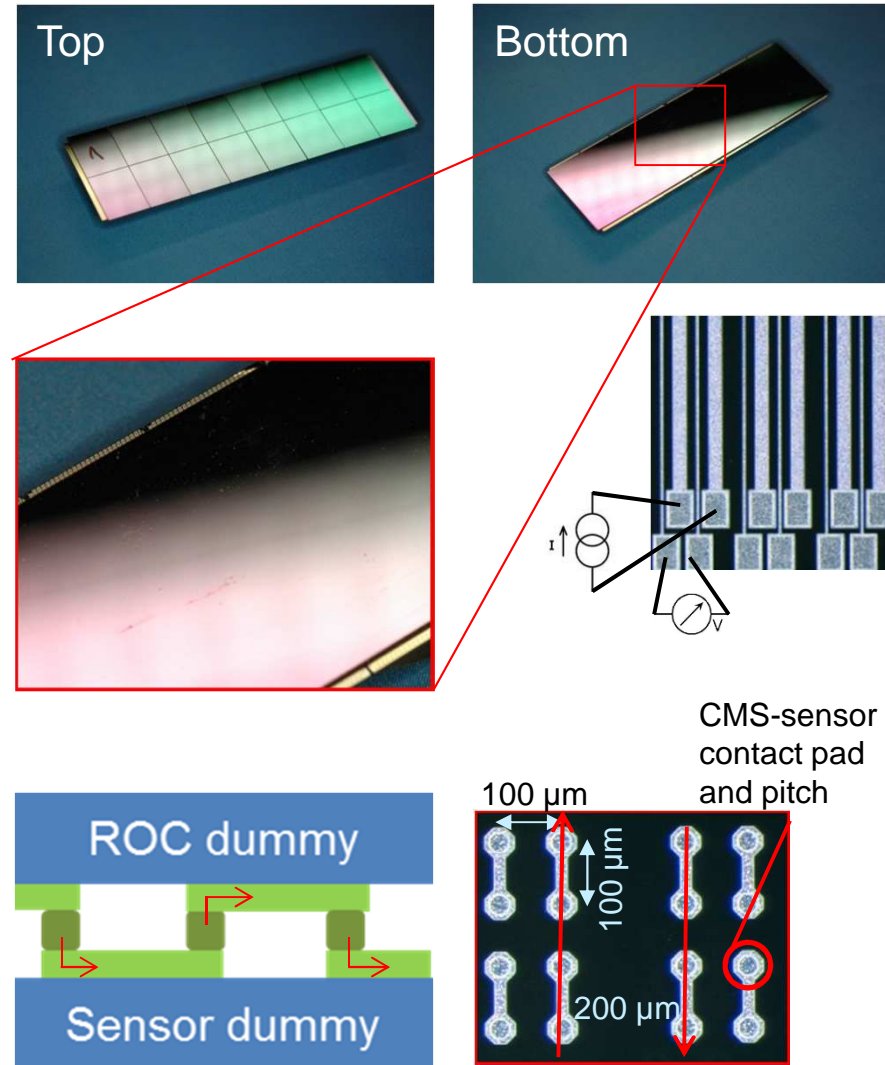
BPIX module dummies

> 4-wire resistance measurements

- 66560 bumps / module
- 416 double columns (dc) / module
- 26 dc / ROC
- 160 bumps / dc
- 4 probe pads / dc
- 104 probe pads / ROC
- 30 μm passivation opening
- single „dead pixel“ \rightarrow open circuit

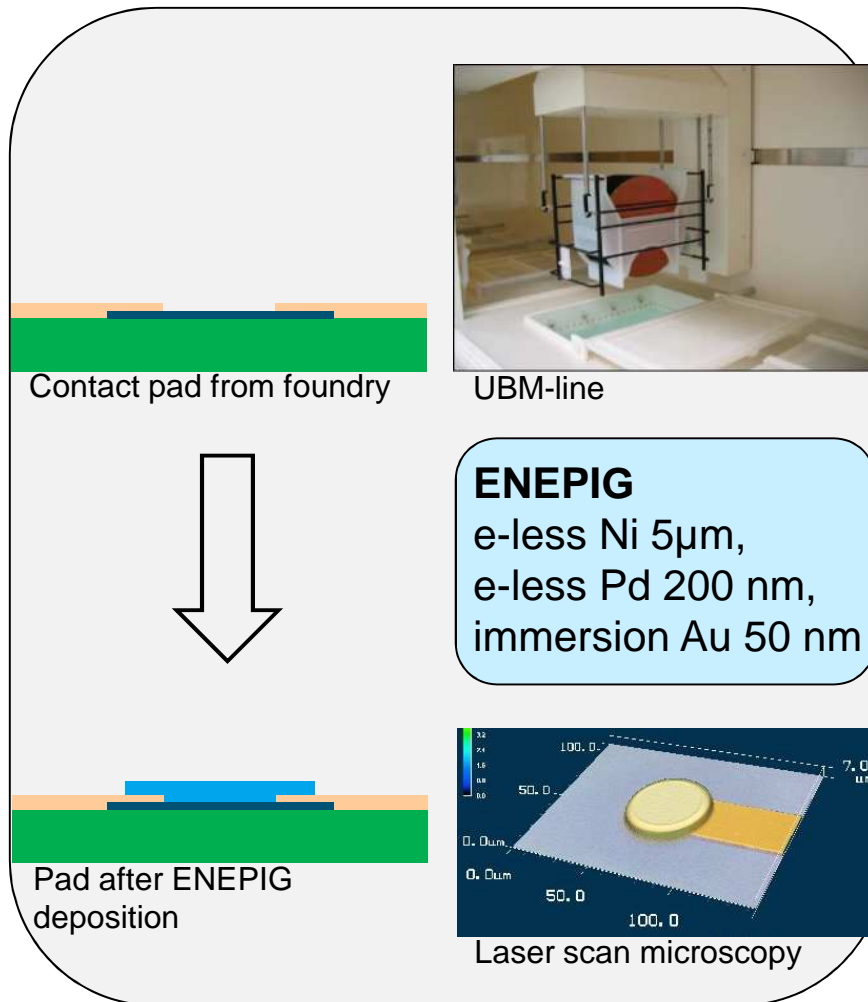
> Future tests also with

- 15 μm opening (real ROC like)
- 285 μm silicon thickness

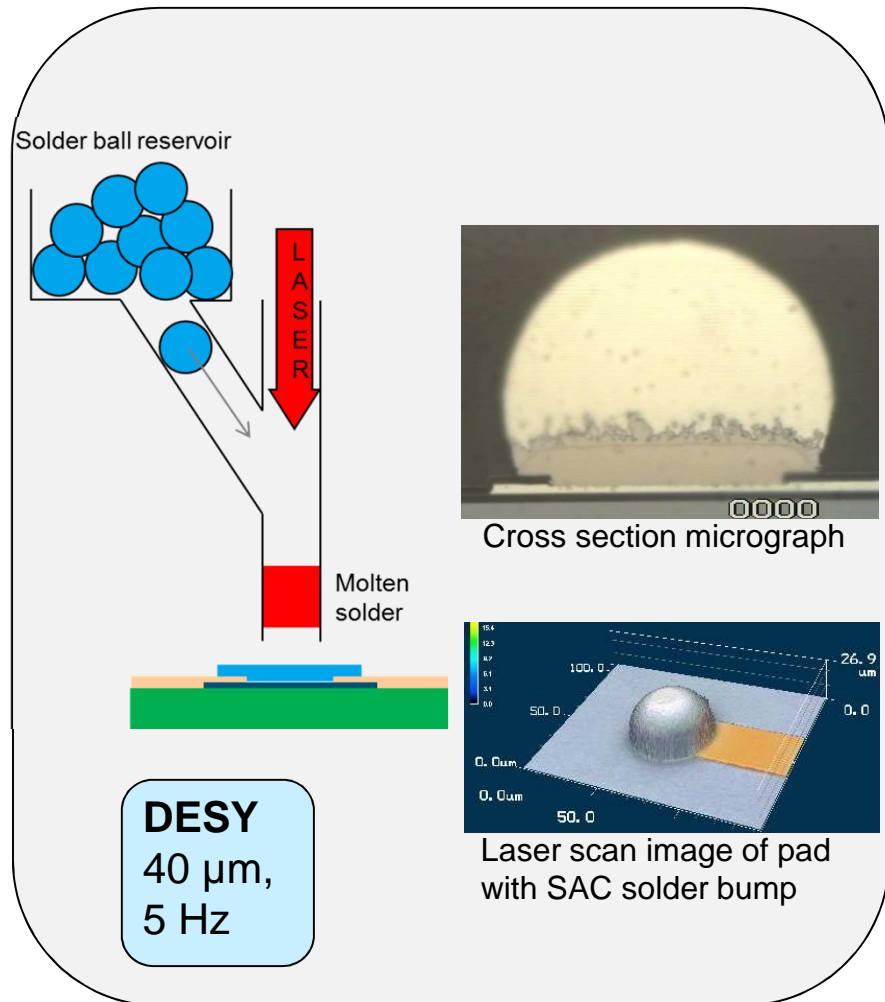


Pac Tech's electroless UBM & solder jetting

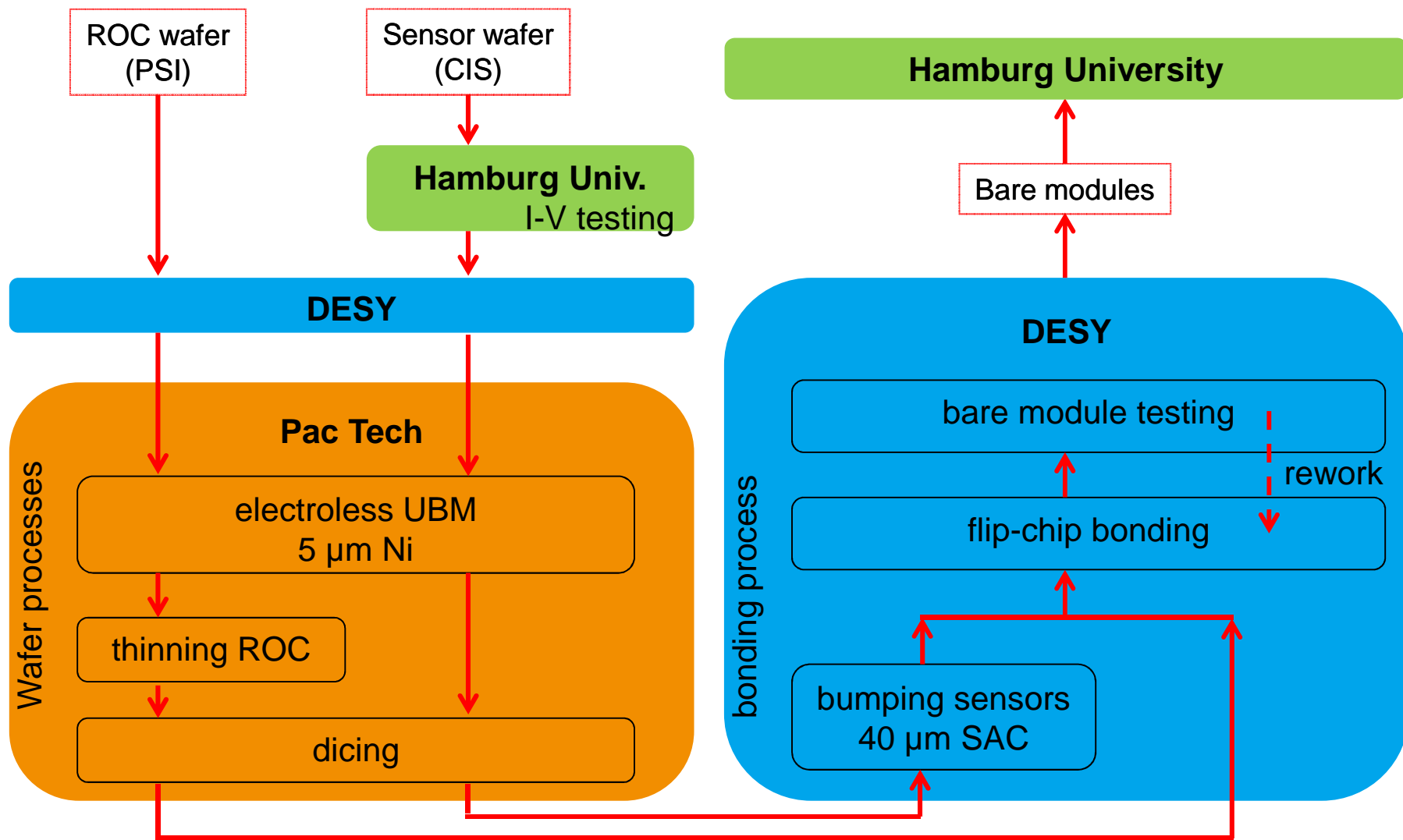
Step 1: UBM Process



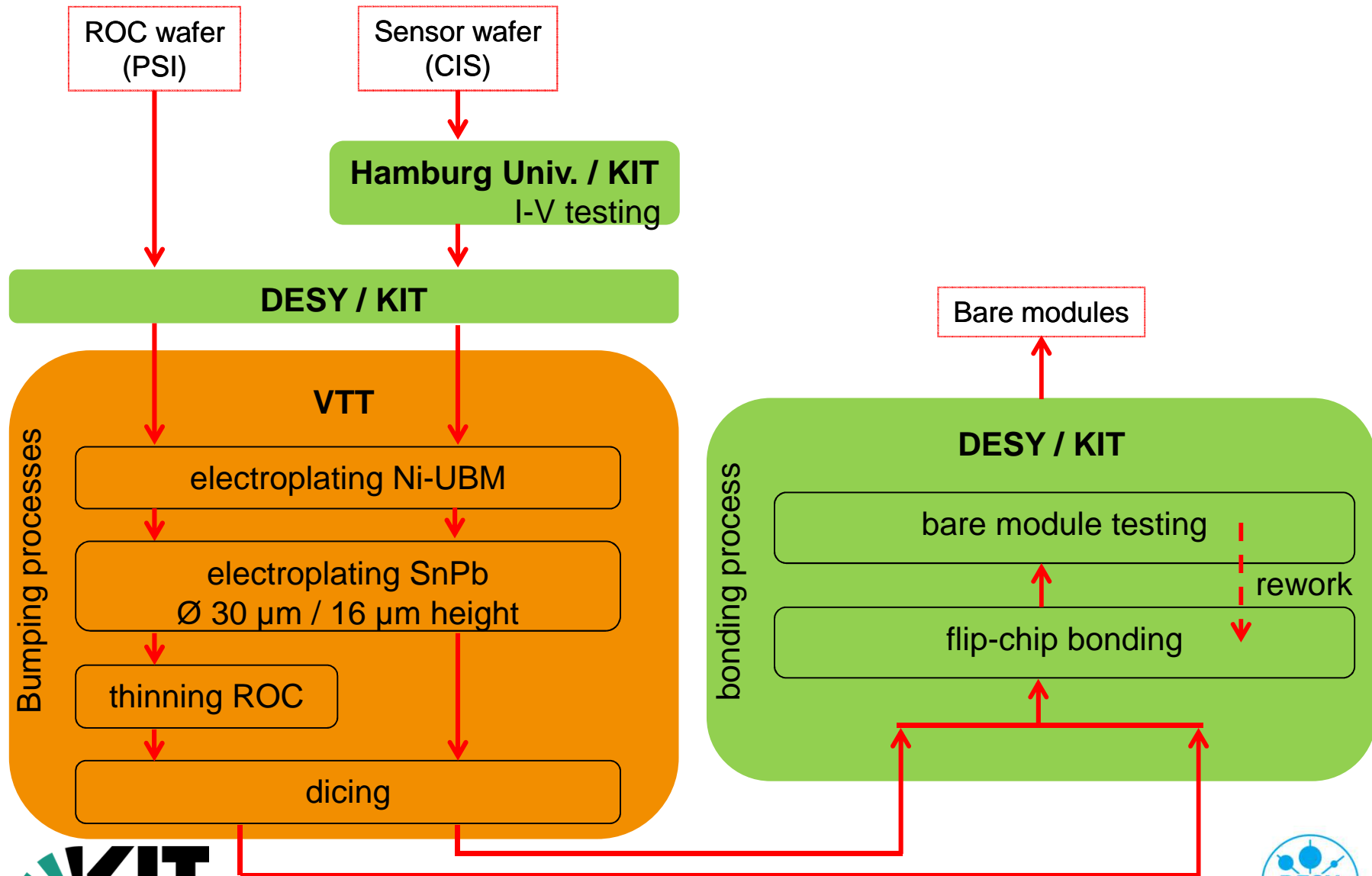
Step 2: Jetting Process



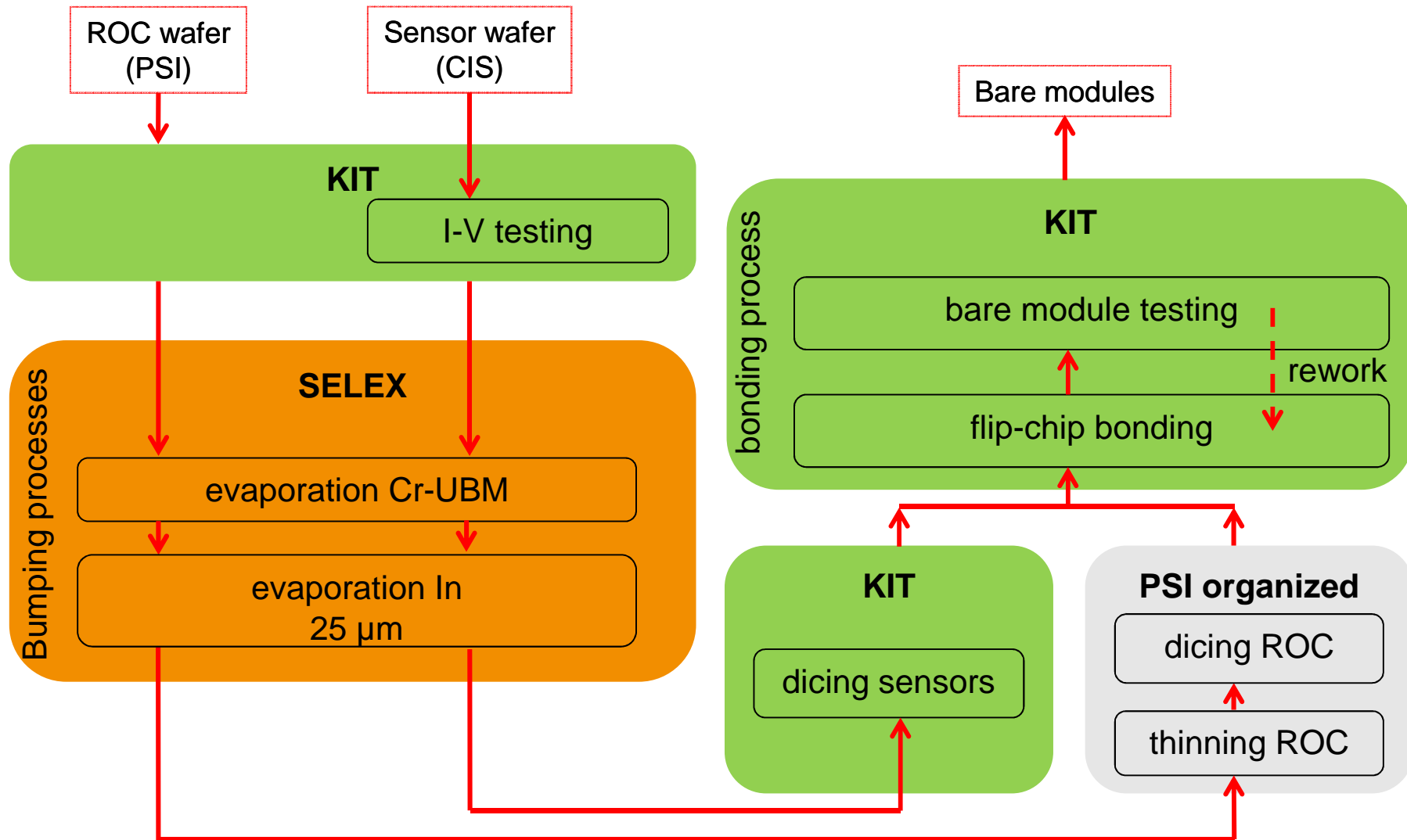
Bump Bonding plan at DESY



Alternative bumping (VTT)

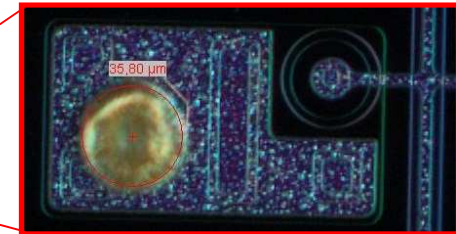
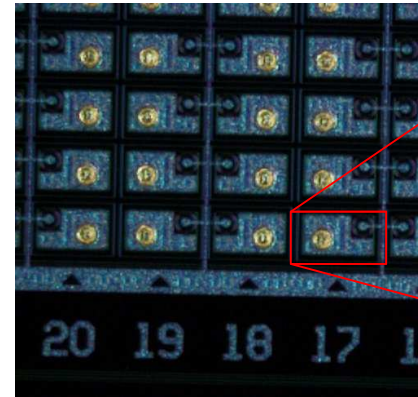


Alternative bumping (SELEX)

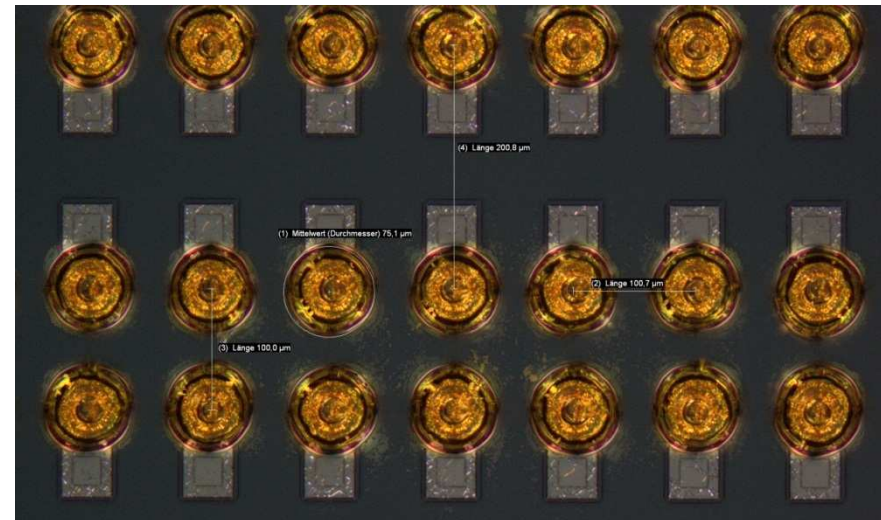


Alternative bumping development @ KIT: gold studs

- > Not for Phase I
- > Tests on CMS sensor samples:
 - conventional ball-wedge bonder
 - ~ 20 bumps / s
 - in development:
 - ~35 μm bumps (15 μm gold wire)
 - envisaged:
 - ~ 25 μm bumps (12.5 μm wire)



CMS sensor pixel with
35.8 μm gold stud



by Stefan Heitz

DPIX Flip-Chip bonding

> Finetech's automated fineplacer FEMTO

- accuracy $< 1 \mu\text{m}$
- KGD probing before bonding
- formic-acid ambient chamber
- complete process parameter monitoring

> Process parameter status

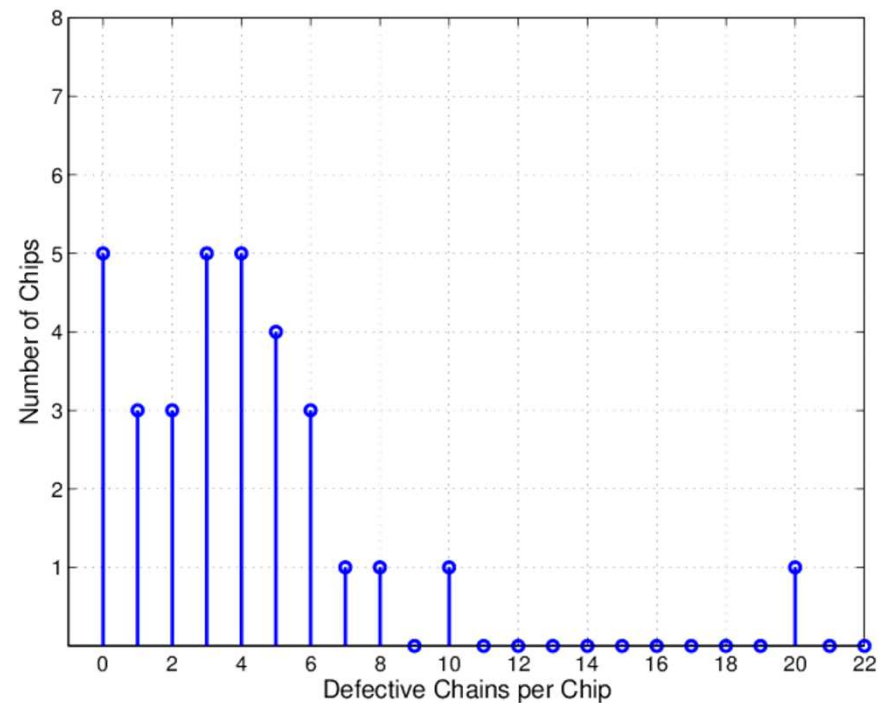
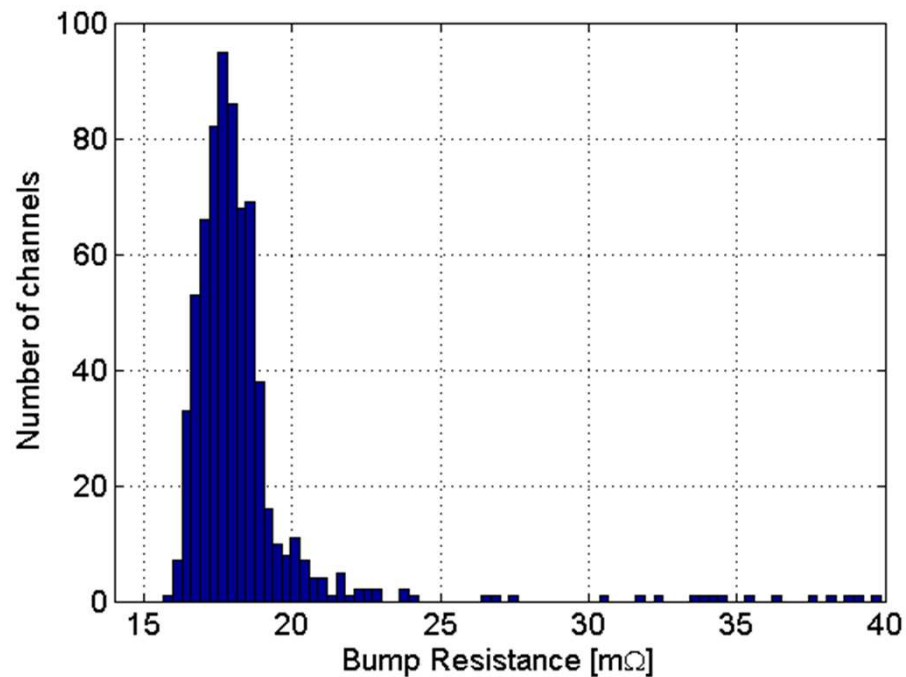
- SAC solder (melting point 217°C)
- $\sim 1 \text{ min./chip}$ (without KGD probing)
- tacking: 100°C hot plate, 210°C Chip, 200 N)
- reflow: $\sim 3 \text{ min.}$, formic-acid, max. 240°C HP
- in development



DESY sample characterization

> Results

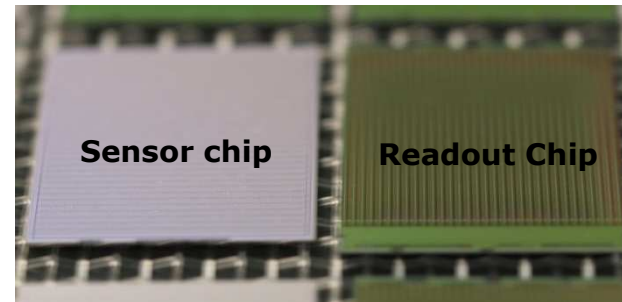
- 84.7% double columns with finite resistance
- residual dc have ≥ 1 bad bump \rightarrow 0.09% module bump yield
- shear result: 21 g/bump
- Bump resistance $\sim 17.5 \text{ m}\Omega$



KIT sample characterization

> ALICE1 spares

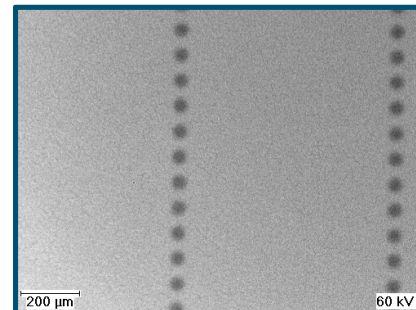
- VTT processed (plated SnPb bumps)
- 8192 bumps/sample
- 425 μm / 50 μm pitch
- 30 μm diameter
- 2.5 g/bump in pull tests



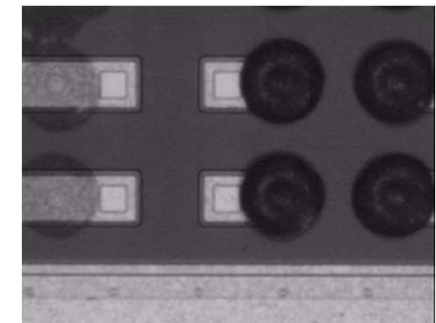
ALICE1 pixel detector ROC and sensor after VTT bumping

> CMS FPIX spares

- KIT Au-studs (35 μm)
- current placing parameter:
380°C hot plate and chip
400 N



X-ray of ALICE1 sample bonded with Femto



X-ray of FPIX sample bonded with Femto

Summary

- > Test structures copying the critical properties of the real modules
 - top metal, passivation
 - pad pitch, pad size, pad count
- > Solder bumping processes
 - DESY inhouse SAC solder jetting (selected)
 - KIT external service (evaluation ongoing)
 - second source services (evaluation ongoing)
- > FC-Bonding machine selected
 - for both sites KIT and DESY
 - automated high accuracy bonder: Femto
 - special features: in-situ reflow and KGD probing prior to attach

Acknowledgments

For their patience, useful comments, supporting work & cooperative attitude

> Equipment vendor

- Pac Tech
- Finetech

> Bumping vendor

- VTT
- SELEX

> DESY people

- Inge Diehl
- Alexander Titze
- Dominik Belzer
- Marco Sessa

> KIT people

- Stefan Heitz

> ALICE collaboration for provision of test samples

Backup

Timetable

- > Bonding machines installed end of 2012
- > DESY's solder jet machine installed mid of 2013 (tendering (20 weeks) and production (20 weeks))
- > KIT/SELEX In-bump test samples Nov. 2012
- > DESY/KIT/VTT SnPb-bump test samples Nov. 2012
- > First real bare module produced summer 2013

Summary

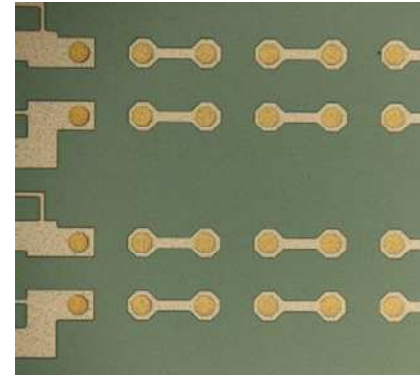
- Test structures copying the critical properties of the real modules
 - top metal, passivation
 - pad pitch, pad size, pad count

Solder Bumping				
Site	UBM	Conducted at	Bumping	Conducted at
DESY	e-less	Pac Tech	jetting 40 μm , 5 Hz	DESY
KIT	plating / evaporation	VTT / SELEX	plating / evaporation 25 μm	VTT / SELEX
Flip-Chip Bonding				
Site	Bonder	Conducted at	Comments	
DESY	Femto	DESY		
KIT	Femto	KIT	Collaboration with INFN & CERN & SELEX	

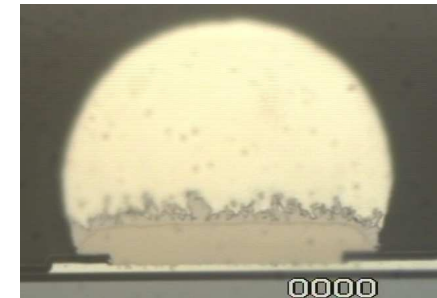
DESY bumping processes overview

> DESY ENEPIG UBM:

- conducted at Pac Tech
- 5 μm e-less Nickel
- 200 nm e-less Palladium
- 50 nm immersion Gold
- isotropic growth
- mushroom like cross section



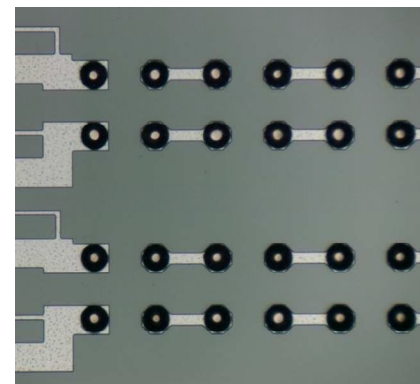
Micrograph of a dummy ROC with ENEPIG UBM



Cross section micrograph of a DESY bump

> SAC305 solder spheres

- in future placed and reflowed at DESY
- lead free ($\text{Sn}96.5\text{Ag}3\text{Cu}0.5$) (%_{wt})
- readily alloyed by vendor
- solder volume controlled by sphere size / vendor



Micrograph of a dummy ROC with jetted solder bumps

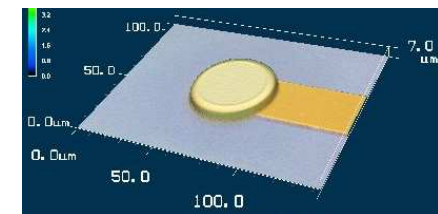
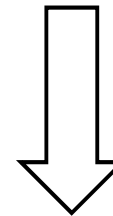
Pac Tech's electroless UBM

> Batch process

- industrial standard process
- high throughput / capacity
- cost-efficient

> wet chemical deposition

- grows on metal
 - ≥ 1 μm metal pad thickness
 - no pin holes
- maskless
- optional backside protection



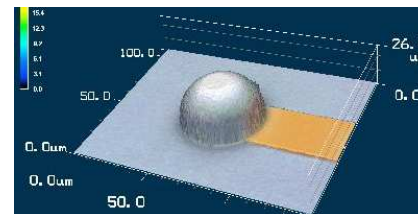
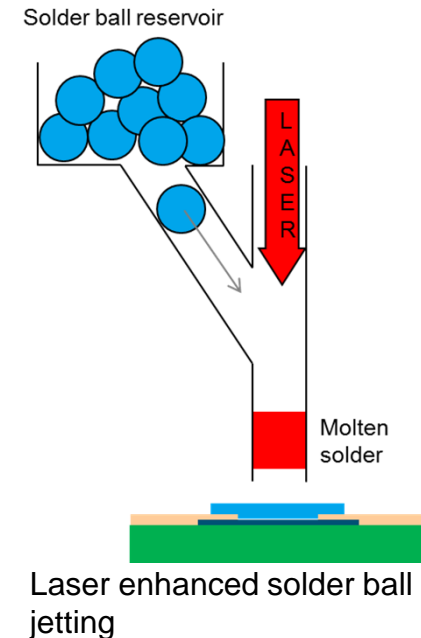
Pac Tech's solder jetting

> Sequential process (≤ 5 bumps / sec)

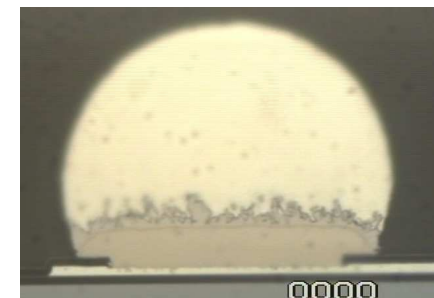
- singulation of sphere from reservoir
- directing to pad through capillary with forced N_2
- melting by laser pulse
- jetting molten solder ball

> High flexibility in

- solder choice
- bump size ($\geq 40 \mu\text{m}$ now $\rightarrow 30 \mu\text{m} \rightarrow 10 \mu\text{m}$)
- bump map (no mask)
- substrate (chip / wafer / 2.5 D ...)

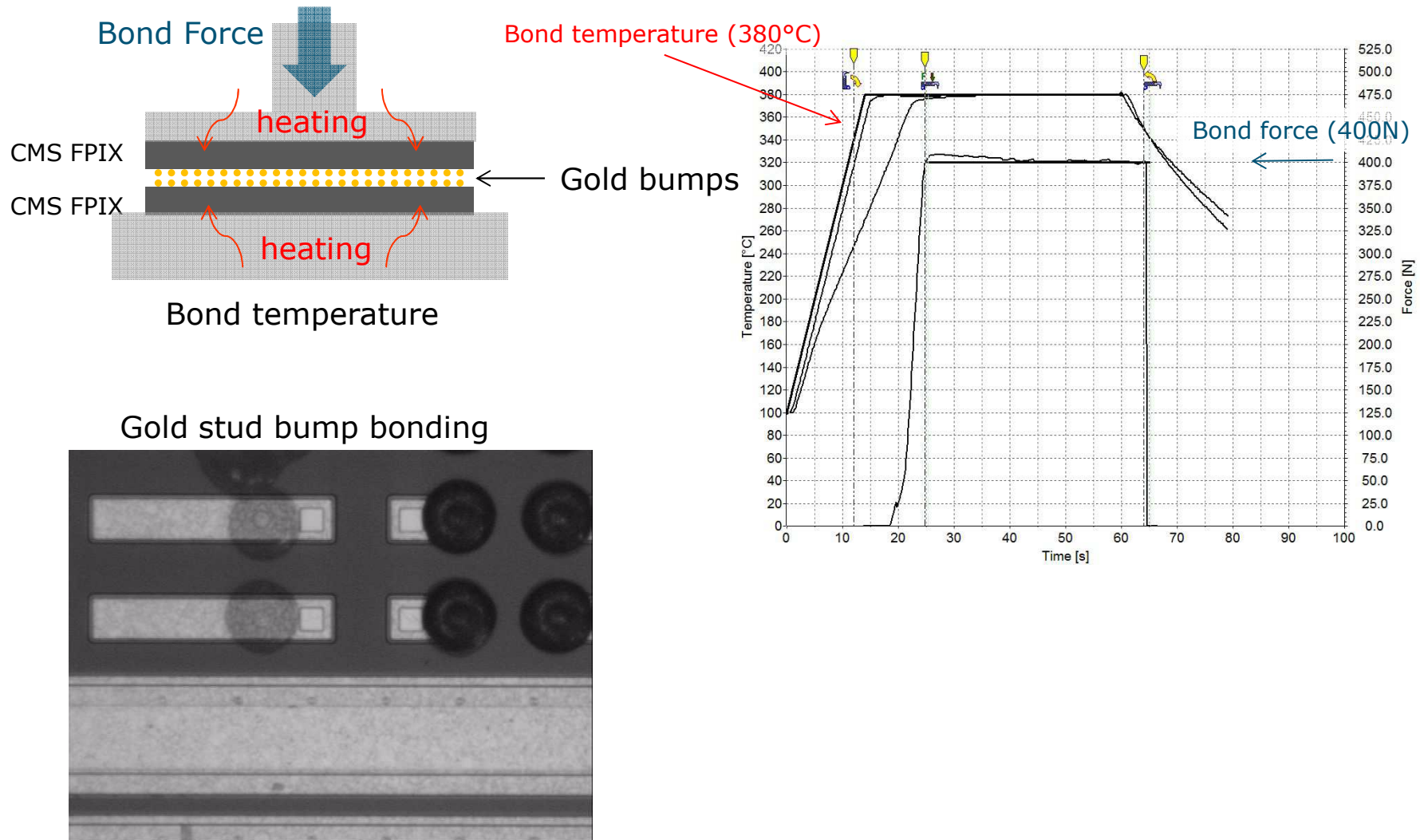


Laser scan image of pad with $40 \mu\text{m}$ SAC solder bump

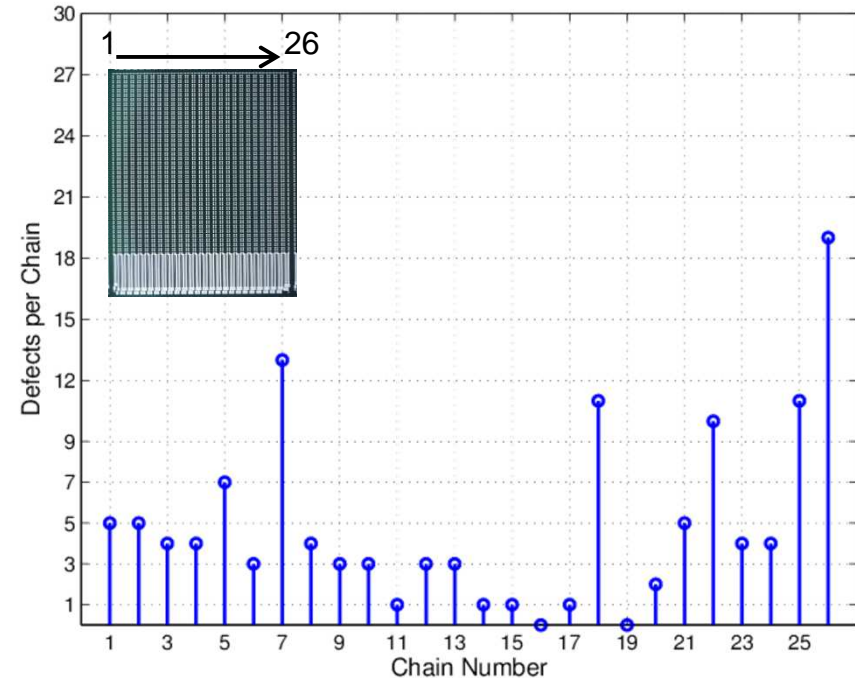
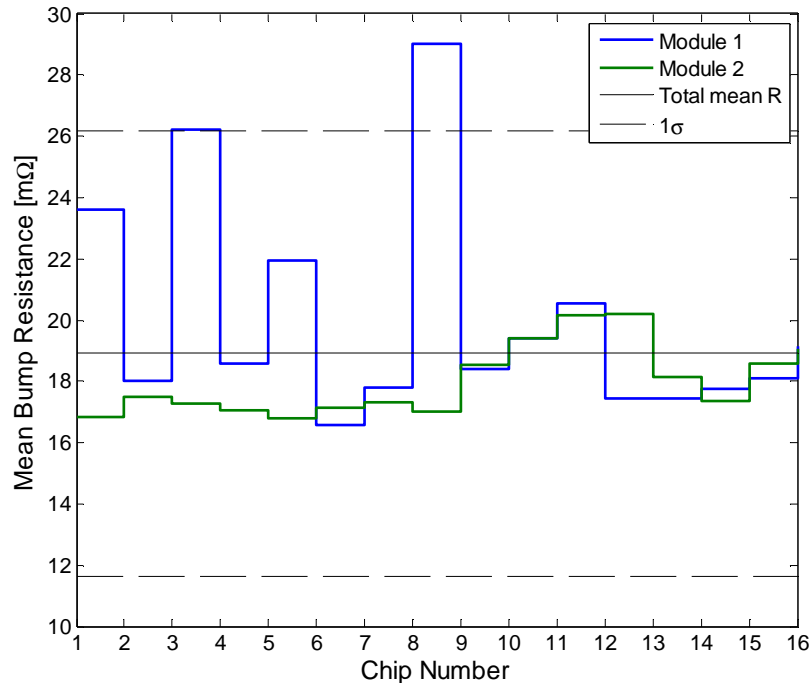


Cross section micrograph

Assembly with Au-studs by Femto



Further (spatial) details in first electrical tests



- > First 8 chip areas of module 1 have been used in several attempts to find correct bonding parameter
- > Very low indication of leveling issues during bonding found